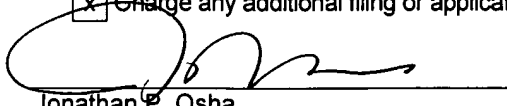
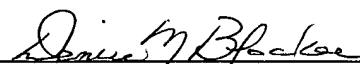
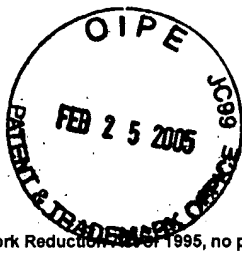


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epwcc/288/\$

AMENDMENT TRANSMITTAL LETTER				Docket No. 03850/010001	
Application No. 09/934,262-Conf. #6459		Filing Date August 21, 2001		Examiner K. T. Nguyen	
				Art Unit 2881	
Applicant(s): Oliver Kienzle et al.					
Invention: APPARATUS AND METHOD FOR EXPOSING A RADIATION SENSITIVE LAYER BY MEANS OF CHARGED PARTICLES AS WELL AS A MASK FOR THIS PURPOSE					
TO THE COMMISSIONER FOR PATENTS					
Transmitted herewith is an amendment in the above-identified application.					
The fee has been calculated and is transmitted as shown below.					
CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid	Number Extra Claims Present	Rate	
Total Claims	17	- 93 =		x	0.00
Independent Claims	4	- 7 =		x	0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					
Other fee (please specify):					
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:					0.00
<input checked="" type="checkbox"/> Large Entity <input type="checkbox"/> Small Entity					
<input checked="" type="checkbox"/> No additional fee is required for this amendment.					
<input type="checkbox"/> Please charge Deposit Account No. _____ in the amount of \$ _____. A duplicate copy of this sheet is enclosed.					
<input type="checkbox"/> A check in the amount of \$ _____ to cover the filing fee is enclosed.					
<input type="checkbox"/> Payment by credit card. Form PTO-2038 is attached.					
<input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. <u>50-0591</u> as described below. A duplicate copy of this sheet is enclosed.					
<input checked="" type="checkbox"/> Credit any overpayment.					
<input checked="" type="checkbox"/> Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.					
 Jonathan P. Osha Attorney Reg. No.: 33,986 OSHA & MAY L.L.P. 1221 McKinney St., Suite 2800 Houston, Texas 77010 (713) 228-8600				Dated: <u>February 25, 2005</u>	
I hereby certify that this correspondence is being deposited with the U.S. Postal Service as Express Mail, Airbill No. EV 535680554US, in an envelope addressed to: MS Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.					
Dated: February 25, 2005		Signature:  (Denise M. Blocker)			



Application No. (if known): 09/934,262

Attorney Docket No.: 03850/010001

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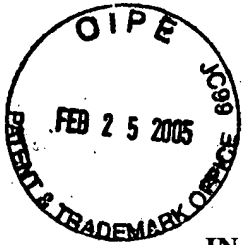
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Reply Under 37 CFR § 1.111 (with attachments) (124 pages)



Docket No.: 03850/010001
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Oliver Kienzle et al.

Application No.: 09/934,262

Art Unit: 2881

Filed: August 21, 2001

Examiner: K. T. Nguyen

For: APPARATUS AND METHOD FOR
EXPOSING A RADIATION SENSITIVE
LAYER BY MEANS OF CHARGED
PARTICLES AS WELL AS A MASK FOR
THIS PURPOSE

REPLY UNDER 37 CFR § 1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed October 25, 2004, please amend the claims as follows:

1. (Currently Amended) A projection apparatus for imaging a pattern of a mask onto a substrate having a radiation sensitive layer by using a beam of charged particles, the mask comprising a membrane layer made of a first material, scattering regions forming the pattern and made of a second material scattering the charged particles more than the membrane layer, a plurality of straightly extending supporting struts spaced apart from one another and supporting the membrane layer together with the scattering regions, and at least one mask region, wherein the projection apparatus comprises:

a beam shaping device for producing the beam of charged particles with a predetermined cross-section in a plane in which the mask extends;